



Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1.-34. (Canceled)

35. (Currently Amended) A method of evaluating a shape of a semiconductor wafer comprising the steps of:

measuring shape data of a semiconductor wafer by scanning a front surface and/or a back surface of the semiconductor wafer;

calculating a differential profile through a differential process of the measured shape data;

analyzing the obtained differential profile and obtaining a surface characteristic of the wafer, ~~and to quantify a shape of the wafer;~~

evaluating a shape of the semiconductor wafer; wherein the shape data of the semiconductor wafer are displacement data of a plane of the semiconductor wafer and/or thickness data of the semiconductor wafer; and

the displacement data of the plane of the semiconductor wafer are displacement of a plane in a direction of thickness in the front surface or the back surface of the wafer when the semiconductor wafer is placed without suction; or

the thickness data of the semiconductor wafer are displacement of a plane in a direction of thickness in one main surface of the wafer when an entire of another main surface of the semiconductor wafer is sucked; or

the displacement data of the plane of the semiconductor wafer are displacement of planes in a direction of thickness in the front surface and the back surface of the wafer when a part of the semiconductor wafer is sucked with a wafer holder, and the thickness data of the semiconductor wafer are difference of the displacement data of planes in

the front surface and the back surface of the wafer when a part of the semiconductor wafer is sucked.

36. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 35, wherein the surface characteristic of the semiconductor wafer is obtained at least in the peripheral portion of the semiconductor wafer.

37. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 35, wherein the shape data of the semiconductor wafer are measured by scanning the front surface and/or the back surface of the semiconductor wafer at an interval of 1 mm or less.

38. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 36, wherein the shape data of the semiconductor wafer are measured by scanning the front surface and/or the back surface of the semiconductor wafer at an interval of 1 mm or less.

39. (Cancelled)

40-46. (Cancelled)

47. (Previously Presented) The method of evaluating a shape of semiconductor wafer according to claim 35, wherein the differential process of the measured shape data is performed by, at first, drawing a shape profile along a radial direction from the measured shape data, and calculating a differential profile through differentiation of the shape profile at a constant interval with setting an arbitrary point as a reference.

48. (Currently Amended) The method of evaluating a shape of a semiconductor wafer according to claim 42~~3~~6, wherein the differential process of the measured shape data is performed by, at first, drawing a shape profile along a radial direction from the measured shape data, and calculating a differential profile through differentiation of the shape profile at a constant interval with setting an arbitrary point as a reference.

49. (Currently Amended) The method of evaluating a shape of a semiconductor wafer according to claim 4437, wherein the differential process of the measured shape data is performed by, at first, drawing a shape profile along a radial direction from the measured shape data, and calculating a differential profile through differentiation of the shape profile at a constant interval with setting an arbitrary point as a reference.

50. (Currently Amended) The method of evaluating a shape of a semiconductor wafer according to claim 4638, wherein the differential process of the measured shape data is performed by, at first, drawing a shape profile along a radial direction from the measured shape data, and calculating a differential profile through differentiation of the shape profile at a constant interval with setting an arbitrary point as a reference.

51. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 47, wherein a second differential profile is used as the differential profile, which is calculated by differentiating the shape profile at a constant interval with setting an arbitrary point as a reference to calculate a first differential profile, and subsequently further differentiating the first differential profile at a constant interval.

52. (Previously Presented) The method of evaluating a shape of semiconductor wafer according to claim 48, wherein a second differential profile is used as the differential profile, which is calculated by differentiating the shape profile at a constant interval with setting an arbitrary point as a reference to calculate a first differential profile, and subsequently further differentiating the first differential profile at a constant interval.

53. (Previously Presented) The method of evaluating a shape of semiconductor wafer according to claim 49, wherein a second differential profile is used as the differential profile, which is calculated by differentiating the shape profile at a constant interval with setting an arbitrary point as a reference to calculate a first differential profile, and subsequently further differentiating the first differential profile at a constant interval.

54. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 50, wherein a second differential profile is used as the differential profile, which is calculated by differentiating the shape profile at a constant interval with setting an arbitrary point as a reference to calculate a first differential profile, and subsequently further differentiating the first differential profile at a constant interval.

55. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 47, wherein the shape profile is differentiated at an interval of 1 mm.

56. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 52, wherein the shape profile is differentiated at an interval of 1 mm.

57. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 53, wherein the shape profile is differentiated at an interval of 1 mm.

58. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 54, wherein the shape profile is differentiated at an interval of 1 mm.

59. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 51, wherein the first differential profile is differentiated at an interval of 1 mm.

60. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 56, wherein the first differential profile is differentiated at an interval of 1 mm.

61. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 57, wherein the first differential profile is differentiated at an interval of 1 mm.

62. (Previously Presented) The method of evaluating a shape of semiconductor wafer according to claim 58, wherein the first differential profile is differentiated at an interval of 1 mm.

63. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 47, wherein removal of components with long wavelengths and/or measured noise is conducted when calculating the differential profile.

64. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 60, wherein removal of components with long wavelengths and/or measured noise is conducted when calculating the differential profile.

65. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 61, wherein removal of components with long wavelengths and/or measured noise is conducted when calculating the differential profile.

66. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 62, a wherein removal of components with long wavelengths and/or measured noise is conducted when calculating the differential profile.

67. (Previously Presented) The method of evaluating a shape of semiconductor wafer according to claim 63, wherein the removal of components with long wavelengths is conducted by means of least squares approximation or high-pass filter.

68. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 64, wherein the removal of components with long wavelengths is conducted by means of least squares approximation or high-pass filter.

69. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 65, wherein the removal of components with long wavelengths is conducted by means of least squares approximation or high-pass filter.

70. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 66, wherein the removal of components with long wavelengths is conducted by means of least squares approximation or high-pass filter.

71. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 63, wherein the removal of the measured noise is performed by means of moving average or low-pass filter.

72. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 64, wherein the removal of the measured noise is performed by means of moving average or low-pass filter.

73. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 65, wherein the removal of the measured noise is performed by means of moving average or low-pass filter.

74. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 66, wherein the removal of the measured noise is performed by means of moving average or low-pass filter.

75. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 35, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the calculated differential profile as a most peripheral data point A1, scanning the differential profile from the most peripheral data point A1 to a center of the wafer and detecting a point where zero is firstly obtained as a Roll Off starting point B1, and performing analysis with setting the Roll Off starting point B1 as a reference.

76. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 68, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the calculated differential profile as a most peripheral data point A1, scanning the differential profile from the most peripheral data point A1 to a center of the wafer and detecting a point where zero is firstly obtained as a Roll Off starting point B1, and performing analysis with setting the Roll Off starting point B1 as a reference.

77. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 69, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the calculated differential profile as a most peripheral data point A1, scanning the differential profile from the most peripheral data point A1 to a center of the wafer and detecting a point where zero is firstly obtained as a Roll Off starting point B1, and performing analysis with setting the Roll Off starting point B1 as a reference.

78. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 70, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the calculated differential profile as a most peripheral data point A1, scanning the differential profile from the most peripheral data point A1 to a center of the wafer and detecting a point where zero is firstly obtained as a Roll Off starting point B1, and performing analysis with setting the Roll Off starting point B1 as a reference.

79. (Currently Amended) The method of evaluating a shape of a semiconductor wafer according to claim 72, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the calculated differential profile as a most peripheral data point ~~A1~~ A1, scanning the differential profile from the most peripheral data

point A1 to a center of the wafer and detecting a point where zero is firstly obtained as a Roll Off starting point B1, and performing analysis with setting the Roll Off starting point ~~24~~B1 as a reference.

80. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 73, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the calculated differential profile as a most peripheral data point A1, scanning the differential profile from the most peripheral data point A1 to a center of the wafer and detecting a point where zero is firstly obtained as a Roll Off starting point B1, and performing analysis with setting the Roll Off starting point B1 as a reference.

81. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 74, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the calculated differential profile as a most peripheral data point A1, scanning the differential profile from the most peripheral data point A1 to a center of the wafer and detecting a point where zero is firstly obtained as a Roll Off starting point B1, and performing analysis with setting the Roll Off starting point B1 as a reference.

82. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 35, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the calculated differential profile as a most peripheral data point A1, scanning the differential profile from the most peripheral data point A1 to a center of the wafer and detecting a position where a maximum value is obtained as a Flip Up maximum slope position C1, and performing analysis with setting the Flip Up maximum slope position C1 as a reference.

83. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 76, wherein the surface characteristic of the semiconductor point of the calculated differential profile as a most peripheral data point A1, scanning the differential profile from the most peripheral data point A1 to a center of the wafer and detecting a position where a maximum value is obtained as a Flip Up maximum slope position C1, and performing analysis with setting the Flip Up maximum slope position C1 as a reference.

84. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 77, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the calculated differential profile as a most peripheral data point A1, scanning the differential profile from the most peripheral data point A1 to a center of the wafer and detecting a position where a maximum value is obtained as a Flip Up maximum slope position C1, and performing analysis with setting the Flip Up maximum slope position C1 as a reference.

85. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 78, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the calculated differential profile as a point of the calculated differential profile as a most peripheral data point A1, scanning the differential profile from the most peripheral data point A1 to a center of the wafer and detecting a position where a maximum value is obtained as a Flip Up maximum slope position C1, and performing analysis with setting the Flip Up maximum slope position C1 as a reference.

86. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 79, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the calculated differential profile as a most peripheral data point A1, scanning the differential profile from the most peripheral data point A1 to a center of the wafer and detecting a position where a maximum value is obtained as a

Flip Up maximum slope position C1, and performing analysis with setting the Flip Up maximum slope position C1 as a reference.

87. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 80, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the calculated differential profile as a most peripheral data point A1, scanning the differential profile from the most peripheral data point A1 to a center of the wafer and detecting a position where a maximum value is obtained as a Flip Up maximum slope position C1, and performing analysis with setting the Flip Up maximum slope position C1 as a reference.

88. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 81, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the calculated differential profile as a most peripheral data point A1, scanning the differential profile from the most peripheral data point A1 to a center of the wafer and detecting a position where a maximum value is obtained as a Flip Up maximum slope position C1, and performing analysis with setting the Flip Up maximum slope position C1 as a reference.

89. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 82, wherein the surface characteristic of the semiconductor wafer is obtained by scanning the differential profile from the calculated Flip Up maximum slope position C1 to a center of the wafer and detecting a position where zero is firstly obtained as a Flip Up starting point D1, and performing analysis with setting the Flip Up starting point D1 as a reference.

90. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 83, wherein the surface characteristic of the semiconductor wafer is obtained by scanning the differential profile from the calculated Flip Up maximum slope

position C1 to a center of the wafer and detecting a position where zero is firstly obtained as a Flip Up starting point D1, and performing analysis with setting the Flip Up starting point D1 as a reference.

91. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 84, wherein the surface characteristic of the semiconductor wafer is obtained by scanning the differential profile from the calculated Flip Up maximum slope position C1 to a center of the wafer and detecting a position where zero is firstly obtained as a Flip Up starting point D1, and performing analysis with setting the Flip Up starting point D1 as a reference.

92. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 85, wherein the surface characteristic of the semiconductor wafer is obtained by scanning the differential profile from the calculated Flip Up maximum slope position C1 to a center of the wafer and detecting a position where zero is firstly obtained as a Flip Up starting point D1, and performing analysis with setting the Flip Up starting point D1 as a reference.

93. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 86, wherein the surface characteristic of the semiconductor wafer is obtained by scanning the differential profile from the calculated Flip Up maximum slope position C1 to a center of the wafer and detecting a position where zero is firstly obtained as a Flip Up starting point D1, and performing analysis with setting the Flip Up starting point D1 as a reference.

94. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 87, wherein the surface characteristic of the semiconductor wafer is obtained by scanning the differential profile from the calculated Flip Up maximum slope position C1 to a center of the wafer and detecting a position where zero is firstly obtained as a

Flip Up starting point D1, and performing analysis with setting the Flip Up starting point D1 as a reference.

95. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 88, wherein the surface characteristic of the semiconductor wafer is obtained by scanning the differential profile from the calculated Flip Up maximum slope position C1 to a center of the wafer and detecting a position where zero is firstly obtained as a Flip Up starting point D1, and performing analysis with setting the Flip Up starting point D1 as a reference.

96. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 51, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the second differential profile calculated as the differential profile as a most peripheral data point A2, scanning the second differential profile from the most peripheral data point A2 to a center of the wafer and detecting a position where zero is firstly obtained as a Flip Up maximum slope position C2, and performing analysis with setting the Flip Up maximum slope position C2 as a reference.

97. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 90, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the second differential profile calculated as the differential profile as a most peripheral data point A2, scanning the second differential profile from the most peripheral data point A2 to a center of the wafer and detecting a position where zero is firstly obtained as a Flip Up maximum slope position C2, and performing analysis with setting the Flip Up maximum slope position C2 as a reference.

98. (Currently Amended) The method of evaluating a shape of a semiconductor wafer according to claim 91, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the second differential profile calculated as the

differential profile as a most peripheral data point ~~A2~~ A2, scanning the second differential profile from the most peripheral data point A2 to a center of the wafer and detecting a position where zero is firstly obtained as a Flip Up maximum slope position C2, and performing analysis with setting the Flip Up maximum slope position C2 as a reference.

99. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 92, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the second differential profile calculated as the differential profile as a most peripheral data point A2, scanning the second differential profile from the most peripheral data point A2 to a center of the wafer and detecting a position where zero is firstly obtained as a Flip Up maximum slope position C2, and performing analysis with setting the Flip Up maximum slope position C2 as a reference.

100. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 93, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the second differential profile calculated as the differential profile as a most peripheral data point A2, scanning the second differential profile from the most peripheral data point A2 to a center of the wafer and detecting a position where zero is firstly obtained as a Flip Up maximum slope position C2, and performing analysis with setting the Flip Up maximum slope position C2 as a reference.

101. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 94, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the second differential profile calculated as the differential profile as a most peripheral data point A2, scanning the second differential profile from the most peripheral data point A2 to a center of the wafer and detecting a position where zero is firstly obtained as a Flip Up maximum slope position C2, and performing analysis with setting the Flip Up maximum slope position C2 as a reference.

102. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 95, wherein the surface characteristic of the semiconductor wafer is obtained by setting a most peripheral point of the second differential profile calculated as the differential profile as a most peripheral data point A2, scanning the second differential profile from the most peripheral data point A2 to a center of the wafer and detecting a position where zero is firstly obtained as a Flip Up maximum slope position C2, and performing analysis with setting the Flip Up maximum slope position C2 as a reference.

103. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 35, wherein a threshold is set to the differential profile, and a locally abnormal value of the shape of the wafer is detected.

104. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 97, wherein a threshold is set to the differential profile, and a locally abnormal value of the shape of the wafer is detected.

105. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 98, wherein a threshold is set to the differential profile, and a locally abnormal value of the shape of the wafer is detected.

106. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 99, wherein a threshold is set to the differential profile, and a locally abnormal value of the shape of the wafer is detected.

107. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 100, wherein a threshold is set to the differential profile, and a locally abnormal value of the shape of the wafer is detected.

108. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 101, wherein a threshold is set to the differential profile, and a locally abnormal value of the shape of the wafer is detected.

109. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 102, wherein a threshold is set to the differential profile, and a locally abnormal value of the shape of the wafer is detected.

110. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 103, wherein the threshold is set at $\pm 0.01 \mu\text{m}/\text{mm}$.

111. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 104, wherein the threshold is set at $\pm 0.01 \mu\text{m}/\text{mm}$.

112. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 105, wherein the threshold is set at $\pm 0.01 \mu\text{m}/\text{mm}$.

113. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 106, wherein the threshold is set at $\pm 0.01 \mu\text{m}/\text{mm}$.

114. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 107, wherein the threshold is set at $\pm 0.01 \mu\text{m}/\text{mm}$.

115. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 108, wherein the threshold is set at $\pm 0.01 \mu\text{m}/\text{mm}$.

116. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 109, wherein the threshold is set at $\pm 0.01 \mu\text{m}/\text{mm}$.

117. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 47, wherein the surface characteristic of the semiconductor wafer obtained along the radial direction is calculated all round the wafer.

118. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 111, wherein the surface characteristic of the semiconductor wafer obtained along the radial direction is calculated all round the wafer.

119. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 112, wherein the surface characteristic of the semiconductor wafer obtained along the radial direction is calculated all round the wafer.

120. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 113, wherein the surface characteristic of the semiconductor wafer obtained along the radial direction is calculated all round the wafer.

121. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 114, wherein the surface characteristic of the semiconductor wafer obtained along the radial direction is calculated all round the wafer.

122. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 115, wherein the surface characteristic of the semiconductor wafer obtained along the radial direction is calculated all round the wafer.

123. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 116, wherein the surface characteristic of the semiconductor wafer obtained along the radial direction is calculated all round the wafer.

124. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 117, wherein the surface characteristic all round the semiconductor wafer is obtained at an interval of a central angle of the wafer of 1° or less.

125. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 118, wherein the surface characteristic all round the semiconductor wafer is obtained at an interval of a central angle of the wafer of 1° or less.

126. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 119, wherein the surface characteristic all round the semiconductor wafer is obtained at an interval of a central angle of the wafer of 1° or less.

127. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 120, wherein the surface characteristic all round the semiconductor wafer is obtained at an interval of a central angle of the wafer of 1° or less.

128. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 121, wherein the surface characteristic all round the semiconductor wafer is obtained at an interval of a central angle of the wafer of 1° or less.

129. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 122, wherein the surface characteristic all round the semiconductor wafer is obtained at an interval of a central angle of the wafer of 1° or less.

130. (Previously Presented) The method of evaluating a shape of a semiconductor wafer according to claim 123, wherein the surface characteristic all round the semiconductor wafer is obtained at an interval of a central angle of the wafer of 1° or less.

131. (Currently Amended) An apparatus for evaluating a shape of a semiconductor wafer, comprising at least:

a shape measuring means for measuring shape data of a semiconductor wafer;

a memorizing means for storing the measured shape data;

a differential processing means for differentiating the stored shape data and calculating a differential profile, and;

a surface characteristic calculating means for obtaining a surface characteristic of the wafer by analyzing the calculated differential profile, wherein the shape measuring means is a means such that displacement data of a plane are obtained as the shape data by measuring displacement of a plane in a direction of thickness in a front surface or a back surface of the semiconductor wafer placed without suction, or wherein the shape measuring means is a means such that thickness data are obtained as the shape data by measuring displacement of a plane in a direction of thickness in one main surface of the semiconductor

wafer of which an entire of another main surface is sucked, or wherein the shape measuring means is a means such that, as the shape data, displacement data of a plane are obtained by measuring displacement of planes in a direction of thickness in a front surface and a back surface of the semiconductor wafer of which a part is sucked by a wafer holder, and thickness data are obtained by measuring difference of the obtained displacement data of the planes in the front surface and the back surface of the wafer.

132-134. (Cancelled)

135. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 131, wherein the differential processing means is a means such that a shape profile along a radial direction is drawn from the shape data, and the differential profile is calculated through differentiation of the shape profile at a constant interval with setting an arbitrary position as a reference.

136-138. (Cancelled)

139. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 135, wherein the differential processing means is a means such that a first differential profile is calculated through differentiation of the shape profile at a constant interval with setting an arbitrary position as a reference, and subsequently a second differential profile is calculated through further differentiation of the first differential profile at a constant interval.

140-142. (Cancelled)

143. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 131, wherein the differential processing means is a means such that removal of components with long wavelengths and/or measured noise is conducted.

144. (Currently Amended) The apparatus for evaluating a shape of a semiconductor wafer according to claim ~~140~~135, wherein the differential processing means is a means such that removal of components with long wavelengths and/or measured noise is conducted.

145. (Currently Amended) The apparatus for evaluating a shape of a semiconductor wafer according to claim ~~141~~139, wherein the differential processing means is a means such that removal of components with long wavelengths and/or measured noise is conducted.

146. (Cancelled)

147. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 131, wherein the surface characteristic calculating means is a means such that a most peripheral point of the differential profile is set as a most peripheral data point A1, the differential profile is scanned from the most peripheral data point A1 to a center of the wafer, a point where zero is firstly obtained is detected as a Roll Off starting point B1, analysis is performed with setting the Roll Off starting point B1 as a reference, and the surface characteristic of the wafer is obtained.

148. (Currently Amended) The apparatus for evaluating a shape of a semiconductor wafer according to claim 144, wherein the surface characteristic calculating means is a means such that a most peripheral point of the differential profile is set as a most peripheral data point ~~A1~~A1, the differential profile is scanned from the most peripheral data point A1 to a center of the wafer, a point where zero is firstly obtained is detected as a Roll Off starting point B1, analysis is performed with setting the Roll Off starting point B1 as a reference, and the surface characteristic of the wafer is obtained.

149. (Currently Amended) The apparatus for evaluating a shape of a semiconductor wafer according to claim 145, wherein the surface characteristic calculating means is a means such that a most peripheral point of the differential profile is set as a most peripheral data point A1, the differential profile is scanned from the most peripheral data point A1 to a center

of the wafer, a point where zero is firstly obtained is detected as a Roll Off starting point B1, analysis is performed with setting the Roll Off starting point ~~B1~~B1 as a reference, and the surface characteristic of the wafer is obtained.

150. (Cancelled)

151. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 131, wherein the surface characteristic calculating means is a means such that a most peripheral point of the differential profile is set as a most peripheral data point A1, the differential profile is scanned from the most peripheral data point A1 to a center of the wafer, a point where the maximum value is obtained is detected as a Flip Up maximum slope position C1, analysis is performed with setting the Flip Up maximum slope position C1 as a reference, and the surface characteristic of the wafer is obtained.

152. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 148, wherein the surface characteristic calculating means is a means such that a most peripheral point of the differential profile is set as a most peripheral data point A1, the differential profile is scanned from the most peripheral data point A1 to a center of the wafer, a point where the maximum value is obtained is detected as a Flip Up maximum slope position C1, analysis is performed with setting the Flip Up maximum slope position C1 as a reference, and the surface characteristic of the wafer is obtained.

153. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 149, wherein the surface characteristic calculating means is a means such that a most peripheral point of the differential profile is set as a most peripheral data point A1, the differential profile is scanned from the most peripheral data point A1 to a center of the wafer, a point where the maximum value is obtained is detected as a Flip Up maximum slope position C1, analysis is performed with setting the Flip Up maximum slope position C1 as a reference, and the surface characteristic of the wafer is obtained.

154. (Cancelled)

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155. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 151, wherein the surface characteristic calculating means is a means such that the differential profile is scanned from the calculated Flip Up maximum slope position C1 to a center of the wafer, a position where zero is firstly obtained is detected as a Flip Up starting point D1, analysis is performed with setting the Flip Up starting point D1 as a reference, and the surface characteristic of the wafer is obtained.

156. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 152, wherein the surface characteristic calculating means is a means such that the differential profile is scanned from the calculated Flip Up maximum slope position C1 to a center of the wafer, a position where zero is firstly obtained is detected as a Flip Up starting point D1, analysis is performed with setting the Flip Up starting point D1 as a reference, and the surface characteristic of the wafer is obtained.

157. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 153, wherein the surface characteristic calculating means is a means such that the differential profile is scanned from the calculated Flip Up maximum slope position C1 to a center of the wafer, a position where zero is firstly obtained is detected as a Flip Up starting point D1, analysis is performed with setting the Flip Up starting point D1 as a reference, and the surface characteristic of the wafer is obtained.

158. (Cancelled)

159. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 139, wherein the surface characteristic calculating means is a means such that a most peripheral point of the second differential profile calculated as the differential profile is set as a most peripheral data point A2, the second differential profile is

scanned from the most peripheral data point A2 to a center of the wafer, a position where zero is firstly obtained is detected as a Flip Up maximum slope position C2, analysis is performed with setting the Flip Up maximum slope a position C2 as a reference, and the surface characteristic of the wafer is obtained.

160. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 156, wherein the surface characteristic calculating means is a means such that a most peripheral point of the second differential profile calculated as the differential profile is set as a most peripheral data point A2, the second differential profile is scanned from the most peripheral data point A2 to a center of the wafer, a position where zero is firstly obtained is detected as a Flip Up maximum slope position C2, analysis is performed with setting the Flip Up maximum slope position C2 as a reference, and the surface characteristic of the wafer is obtained.

161. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 157, wherein the surface characteristic calculating means is a means such that a most peripheral point of the second differential profile calculated as the differential profile is set as a most peripheral data point A2, the second differential profile is scanned from the most peripheral data point A2 to a center of the wafer, a position where zero is firstly obtained is detected as a Flip Up maximum slope position C2, analysis is performed with setting the Flip Up maximum slope position C2 as a reference, and the surface characteristic of the wafer is obtained.

162. (Cancelled)

163. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 131, wherein the surface characteristic calculating means is a means such that a threshold is set to the differential profile, and a locally abnormal value of the shape of the wafer is detected.

164. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 160, wherein the surface characteristic calculating means is a means such that a threshold is set to the differential profile, and a locally abnormal value of the shape of the wafer is detected.

165. (Previously Presented) The apparatus for evaluating a shape of a semiconductor wafer according to claim 161, wherein the surface characteristic calculating means is a means such that a threshold is set to the differential profile, and a locally abnormal value of the shape of the wafer is detected.

166. (Cancelled)